

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: XSIL TECHNOLOGY LIMITED #2

Serial No. Art Unit

Filed: Examiner:

For: LASER MACHINING

Assistant Commissioner for Patents
Washington, D.C. 20231
USA

Sir,

INFORMATION DISCLOSURE STATEMENT

In the interests of candor, the Applicants wish to draw the Examiner's attention to following prior art of which Applicants have become aware.

Application no. (NAME), date

US 5 266 532	RUSSELL ET AL	11-30-1993
US 5 322 988	RUSSELL ET AL	07-21-1994
US 5 385 633	RUSSELL ET AL	01-31-1995
US 5 348 609	RUSSELL ET AL	09-20-1994
US 5 164 324	RUSSELL ET AL	11-17-1992
US 3 866 398	VERNON, JR, ET AL	02-18-1975
US 2002/050489	HAYASAKA NOBUO ET AL	05-02-2002
JP 61-140396	FUJIKURA	06-27-1986
WO 03 000456	SEPPELT KONRAD; POPKOVA VERA YAKOVLEVNA; SHAFEEV GEORGII	01-03-2003
WO 03 028943 A	LAMBDA PHYSIK APPLIC CT L L C	04-10-2003
WO 03 028941 A	SCAGGS MICHAEL J	04-10-2003
WO 97.24768	PACIFIC SOLAR PTY LTD; YOUNG TREVOR	07-10-1997

10/523846
Rec'd PCT/PTO 07 FEB 2005

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HOLLMAN RICHARD F;

03-16-1995

ELLIOTT DAVID J; SINGER

DANIEL K; UVT

Patents Abstract of Japan, vol. 009, no 100 2 May 1985 & JP 59 225896 A (Handoutai Enerugii Kenkyusho: KK) 18 December 1984

Lim P et al, "Laser-assisted liquid film etching", Applied Physics Letters, American Institute of Physics. New York, US, vol. 62, no. 25, 21 June 1993

Database WPI, Section CH, Week 198637, Derwent Publications Ltd., London, GB; Class L03, AN 1986-240798 & JP 61 053731 A (Anritsu Electric Co Ltd), 17 March 1986

Svorcik V et al, "Laser-stimulated etching of n-Si in Aqueous Solutions", Materials Letters, North Holland Publishing Company. Amsterdam, NL. Vol. 9, no.5/6, 1 March 1990,

Patents Abstract of Japan, vol. 012, no. 330 (E-655), 7 September 1988 & JP 63 094657 A (NEC CORP), 25 April 1988

The relevance of the references is as indicated in the attached International and GB Search Reports.

The above references are listed on the attached Form PTO/SB/08A and the Examiner is respectfully requested to make them of record.

Respectfully submitted

Date: Jan 7, 2005

By: 
Douglas S Rupert
Reg. No. 44,434

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PTO/SB/08A (08-00)

Approved for use through 10/31/2002. OMB 0651-0031

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

of

Complete if Known 105523846

Application Number _____

Filing Date _____

First Named Inventor BOYLE, Adrian

First Named Inventor: BOTELLI, Adriana
Group Ad Unit:

Group A/H Unit

Examiner Name _____

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

Examiner Signature		Date Considered	
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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Sheet

of

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107523846

Application Number

Filing Date

First Named Inventor

Group Art Unit

Examiner Name

Attorney Docket Number

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		Patent Abstracts of Japan, vol. 009, no. 100 (M-376), 2 May 1985 & JP 59 225896 A (HANDOUTAI ENERUGII KENKYUSHO: KK), 18 December 1984	
		LIM P ET AL, "Laser-Assisted Liquid Film Etching", Applied Physics Letters, American Institute of Physics. New York, US, vol. 62, no.25, 21 June 1993, pages 3345-3347, XP000380997, ISSN: 0003-6951, page 3345	
		DATABASE WPI, Section Ch, Week 198637, Derwent Publications Ltd., London, GB: Class L03, AN 1986-240798 XP02261883 & JP 61 053731 A (ANRITSU ELECTRIC CO LTD), 17 March 1986, abstract; figure 1	
		SVORCIK V ET AL: "Laser-Stimulated Etching of N-Si in aqueous solutions" Material Letters, North Holland Publishing Company, Amsterdam, NL, vol.9, no.5/6, 1 March 1990, pages 204-206 XP000127337, ISSN: 0167-577X, the whole document	
		Patents Abstracts of Japan, vol. 012, no. 330 (E-655), 7 September 1988 & JP 63 094657 A (NEC CORP), 25 April 1988,	

Examiner Signature	Date Considered
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² Applicant is to place a check mark here if English language Translation is attached.

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